

Development of promising techniques for a new generation of plasma diagnostics

Antoine Durocher-Jean, Luc Stafford

Groupe PPHARE, Département de physique, Université de Montréal



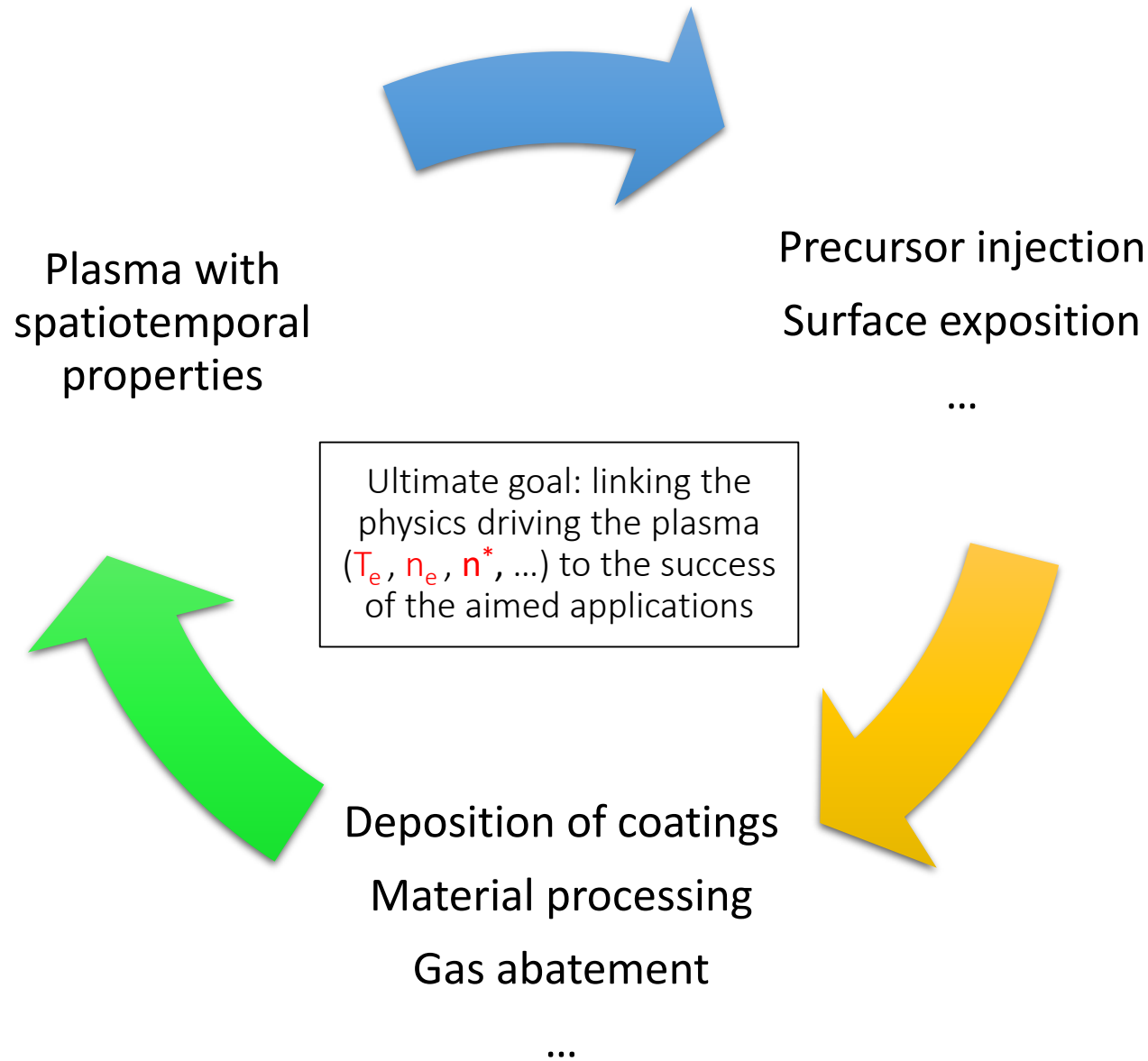
Laura-Isabelle Dion-Bertrand,
Sébastien Blais-Ouellette



Hubert Jean-Ruel



Motivations



Popular diagnostics:

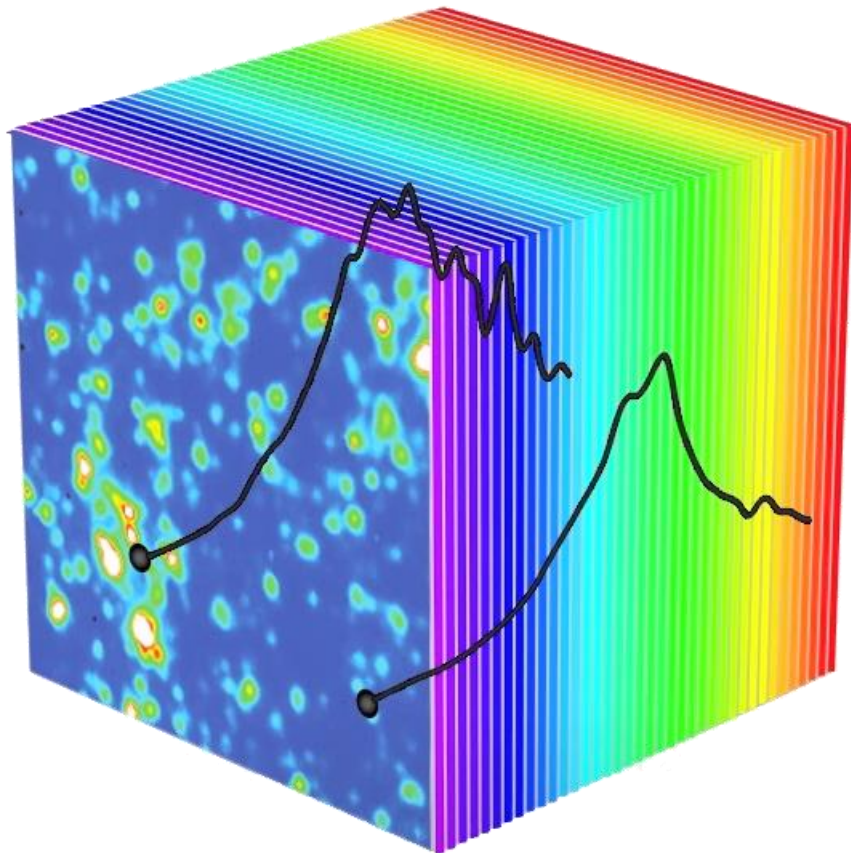
- Probes (Langmuir, thermal...)
- Optical emission/absorption spectroscopy
- Laser diagnostics (LIF, Thomson scattering...)
- Mass spectrometry
- Interferometry
- ...

Any other nice technologies out there..?

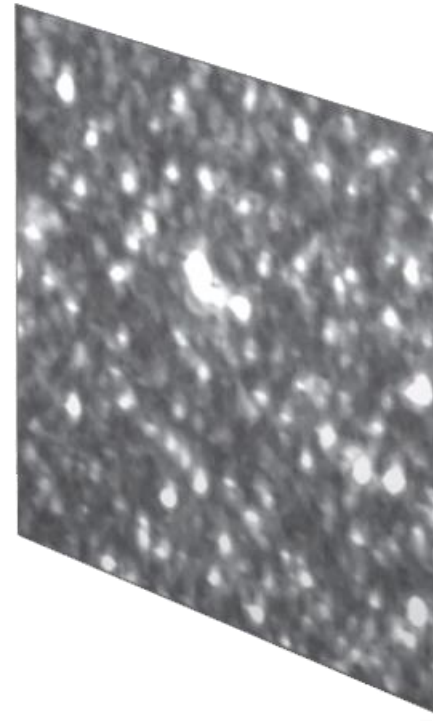
Hyperspectral imaging

Hyperspectral imaging

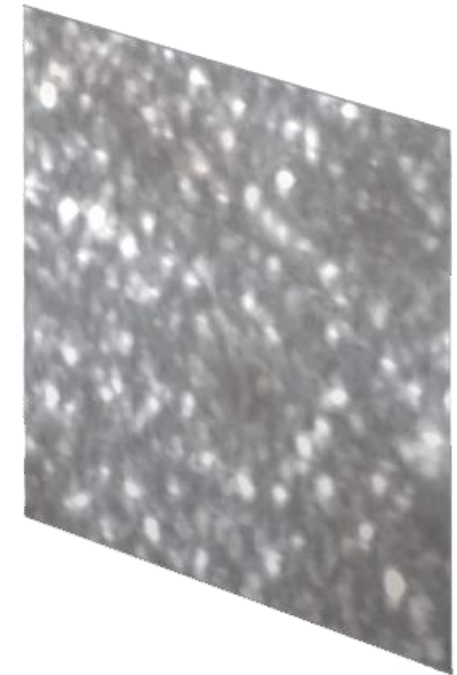
Already popular in: Raman imaging, cellular imaging, photovoltaic characterization



Each camera pixel
=
spectrum



$\lambda = 450$

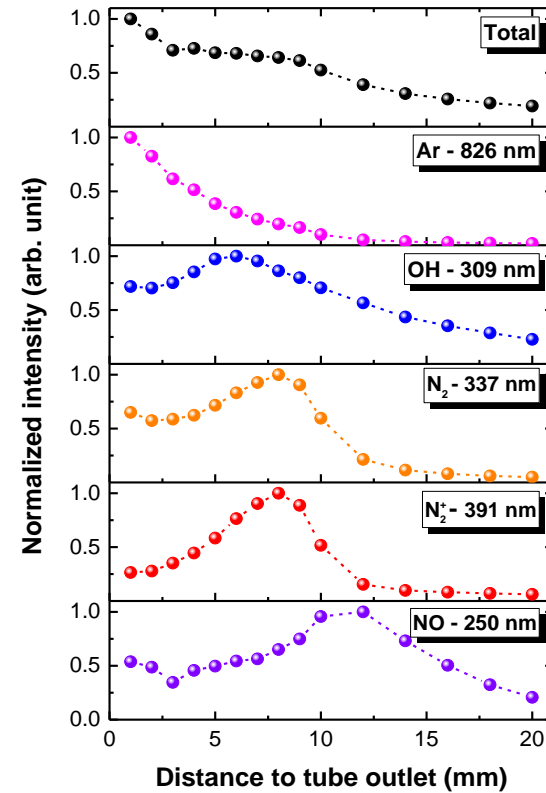
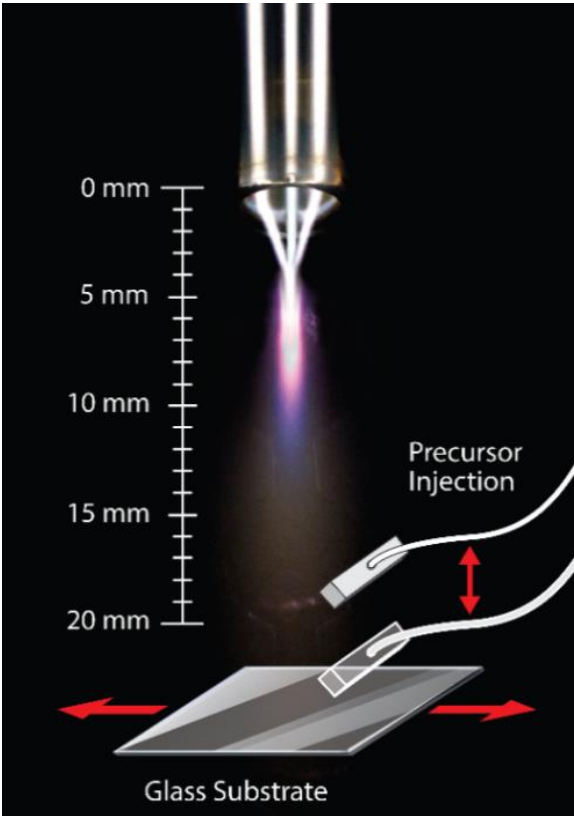


$\lambda = 650$

Image for each wavelength!
Like having 1000+ filters with a much narrower bandpass

Hyperspectral imaging

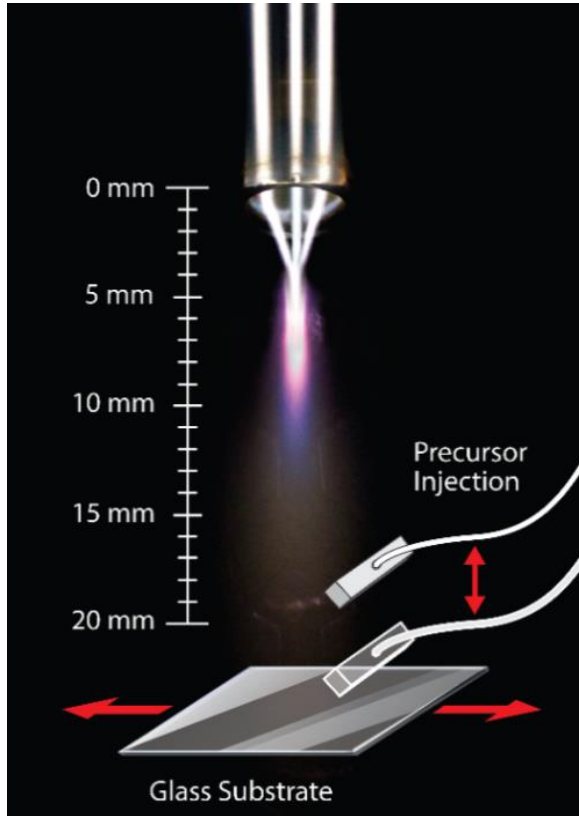
Why is this awesome?



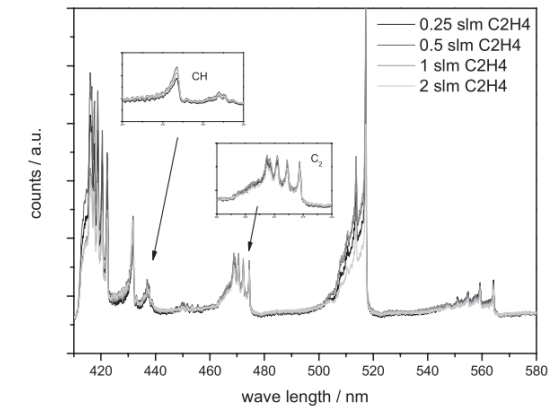
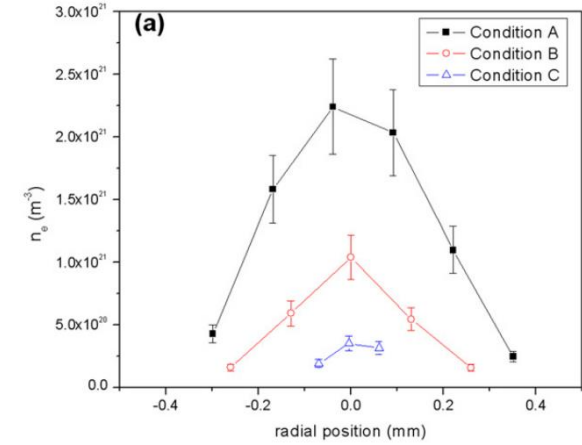
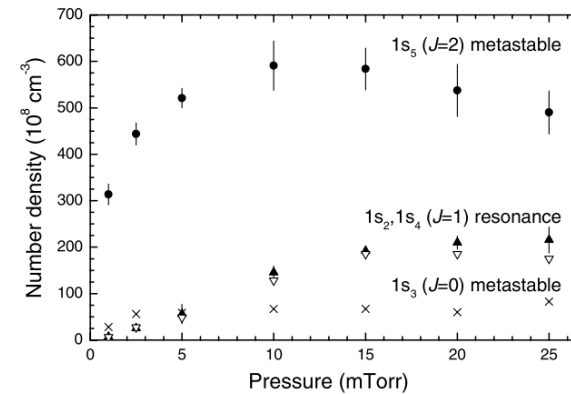
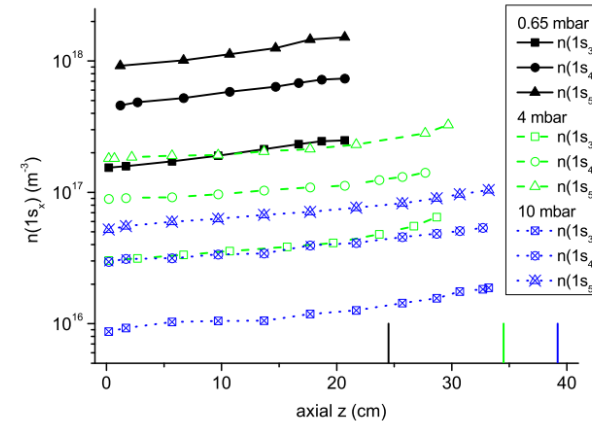
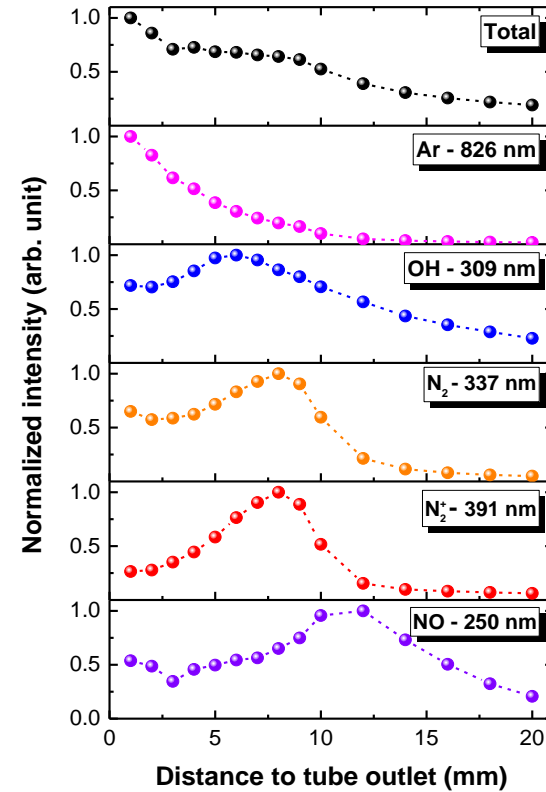
A. Durocher-Jean, I. R. Durán, S. Asadollahi, G. Laroche, and L. Stafford, Plasma Process. Polym. e1900229 (2020)

Hyperspectral imaging

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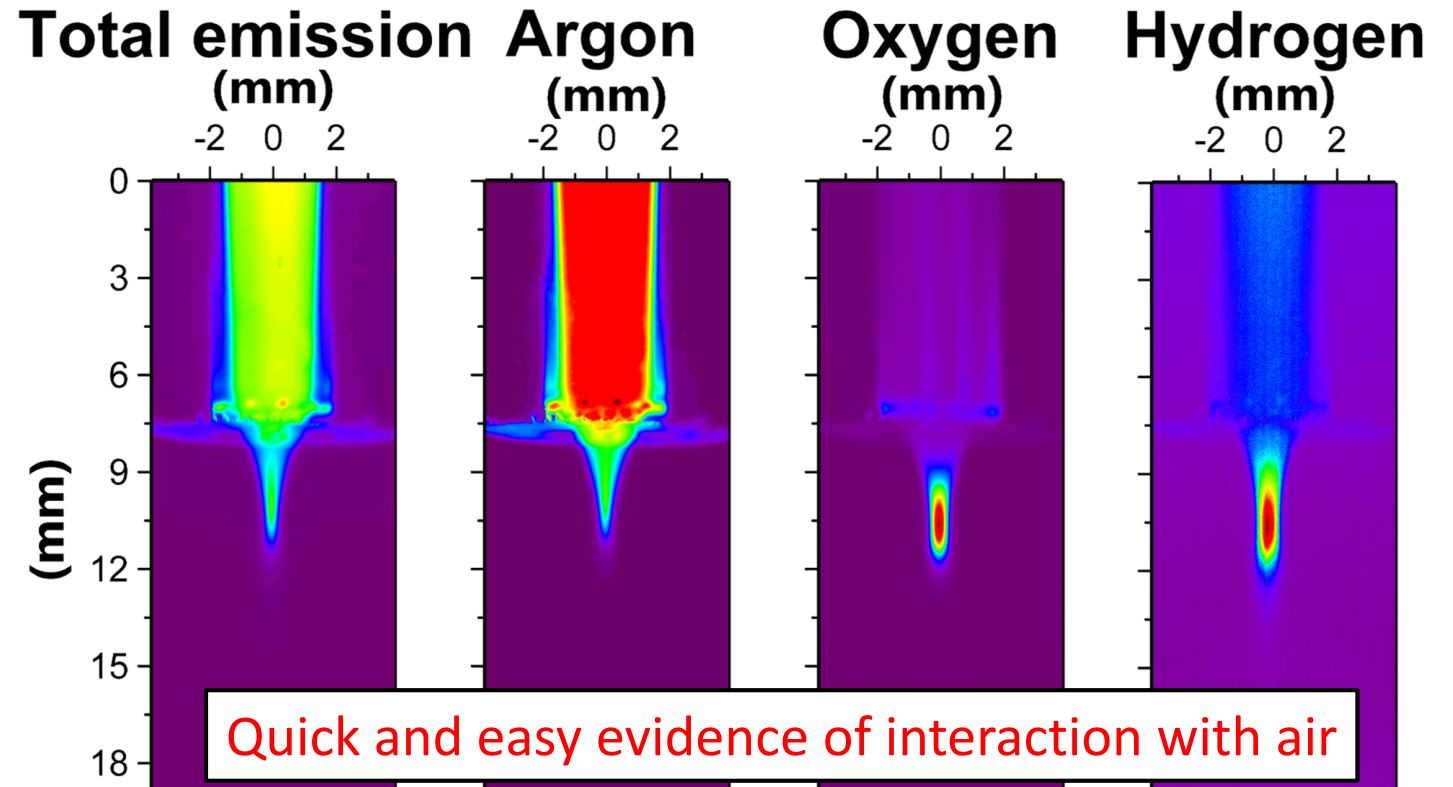
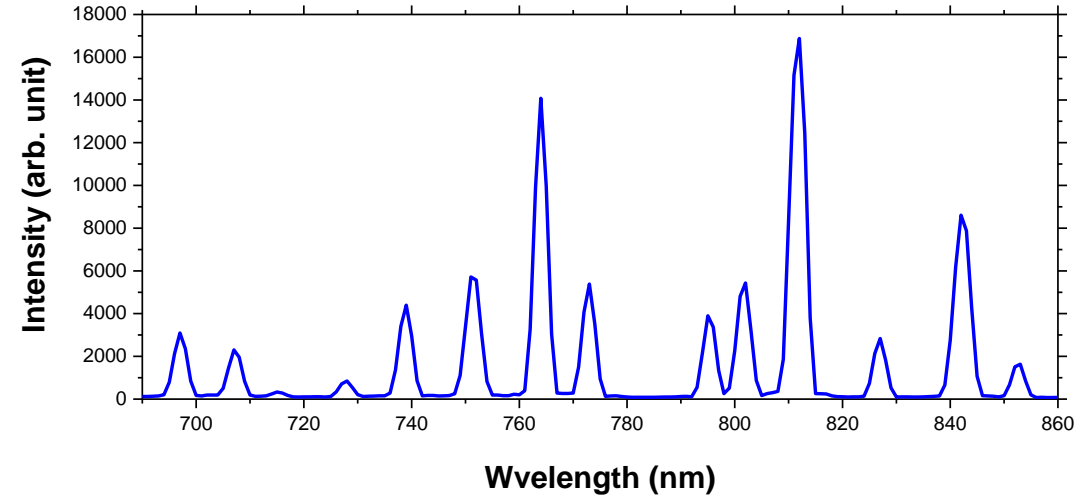
Just how representative of the whole plasma are these measurements?

Hyperspectral imaging

Atmospheric pressure
microwave plasma jet

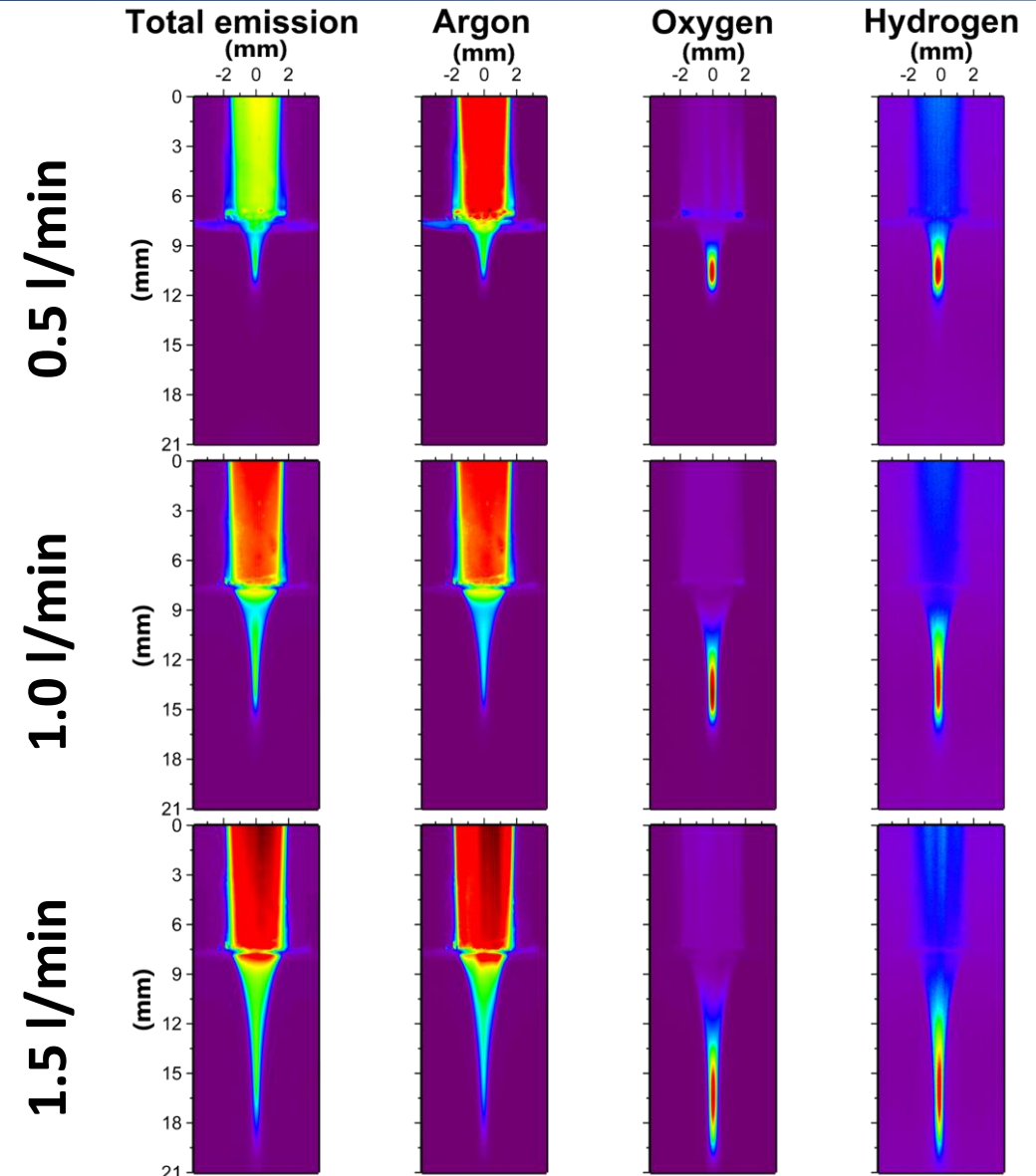


~4 ms integration time
400 - 900 nm
=
Hypercube in <2min



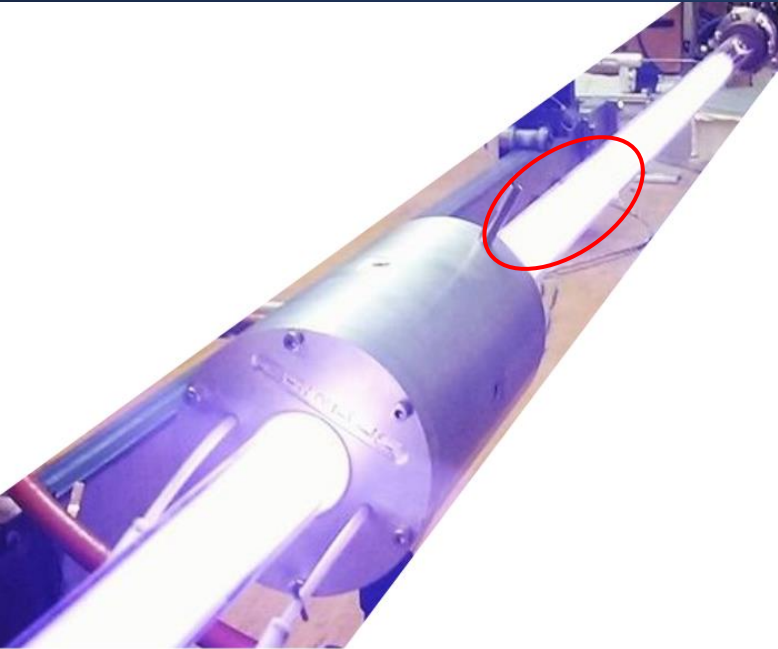
Hyperspectral imaging

Atmospheric pressure
microwave plasma jet



Influence of the Ar flow rate on the mixing with air

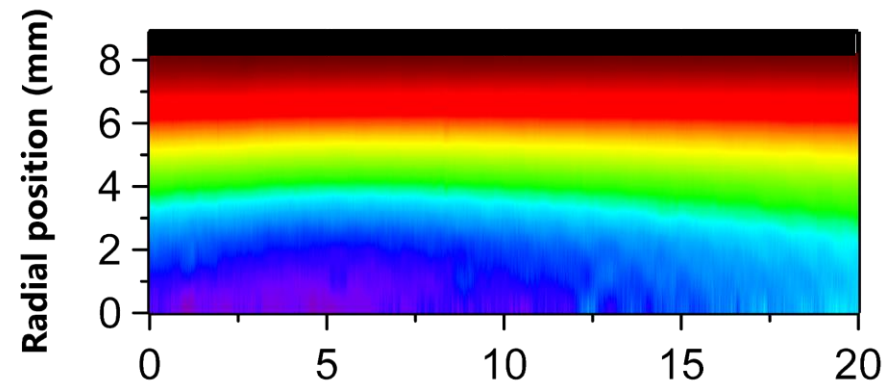
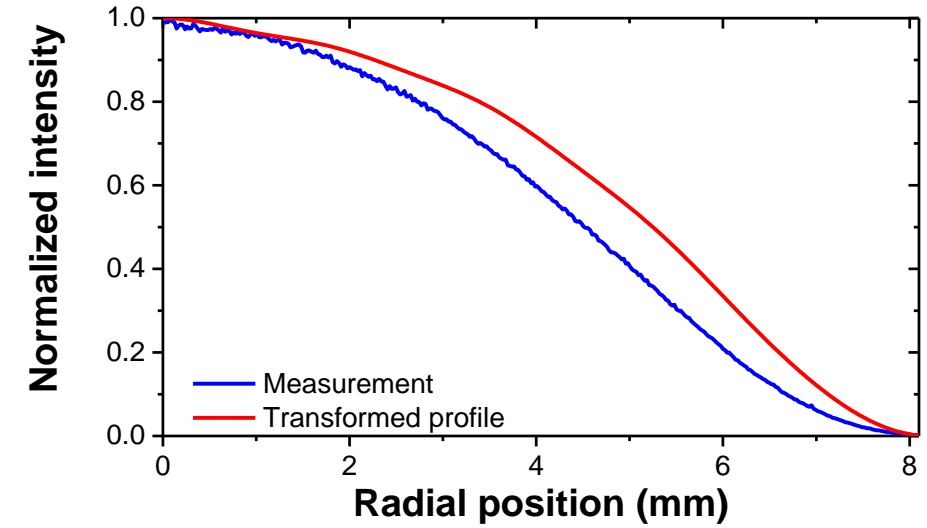
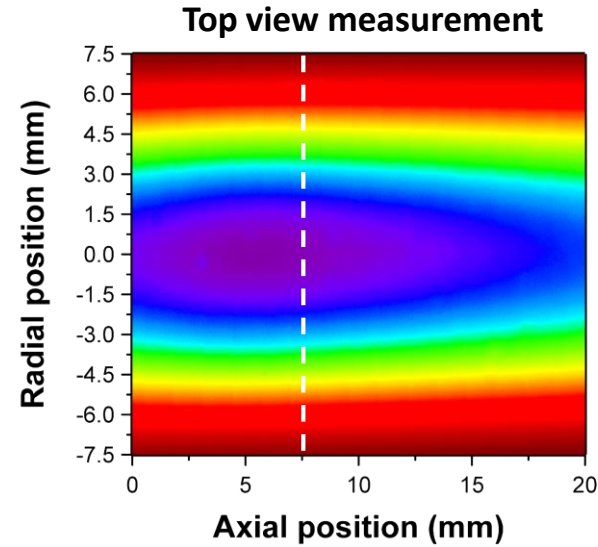
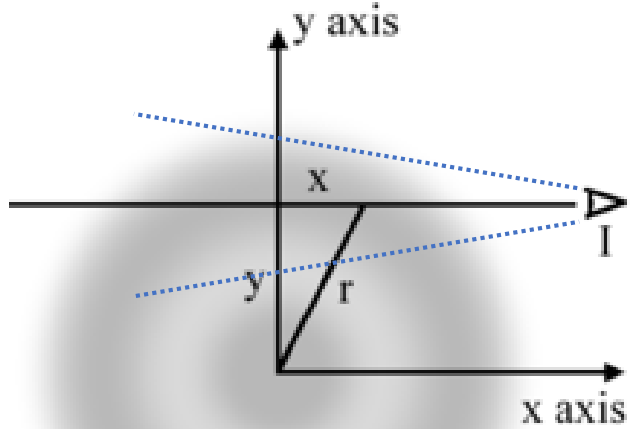
Plasma tomography



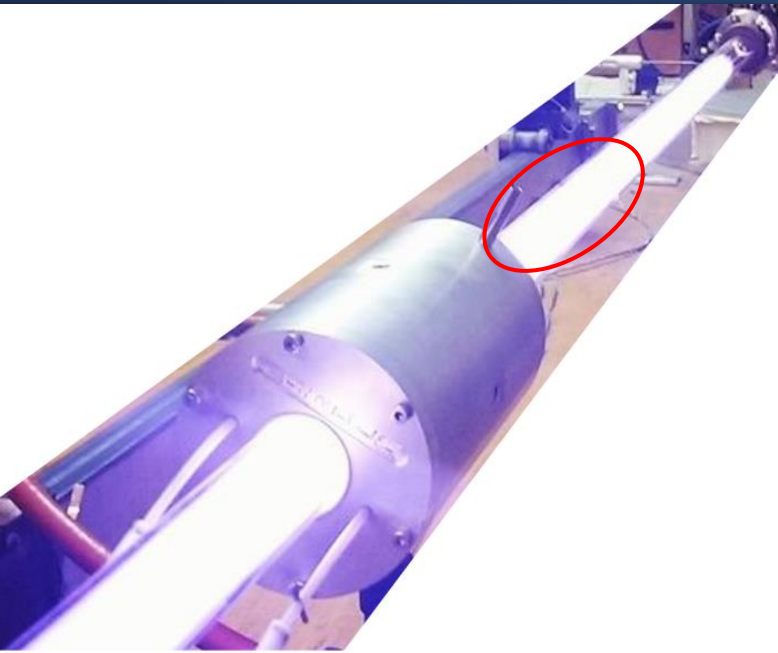
The Abel transform

$$F(y) = 2 \int_y^\infty \frac{f(r)r}{\sqrt{r^2 - y^2}} dr \quad \leftrightarrow \quad f(r) = -\frac{1}{\pi} \int_r^\infty \frac{dF}{dy} \frac{dy}{\sqrt{y^2 - r^2}}$$

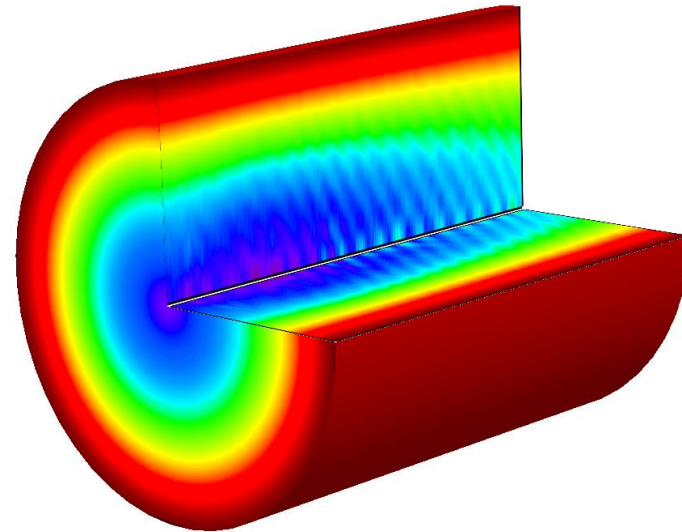
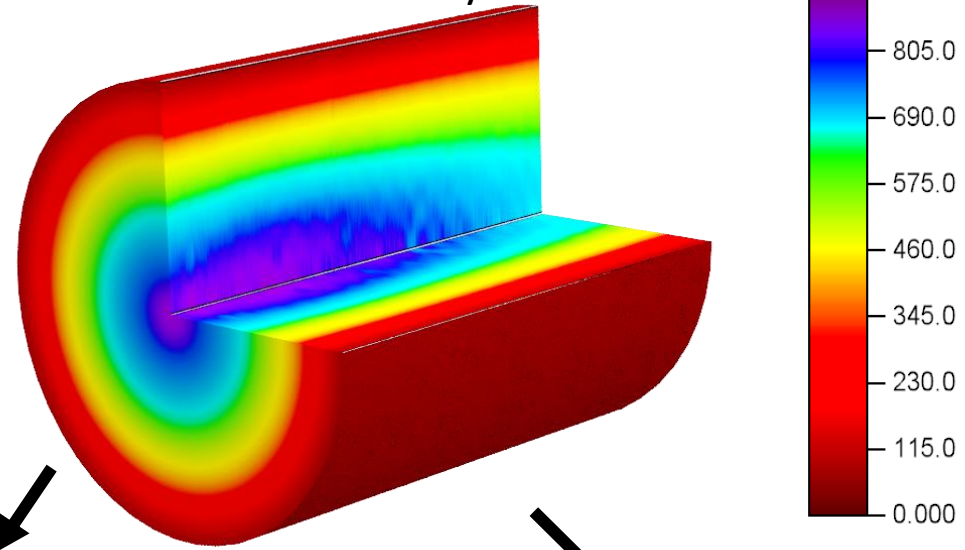
Better spatial resolution = more accurate transform



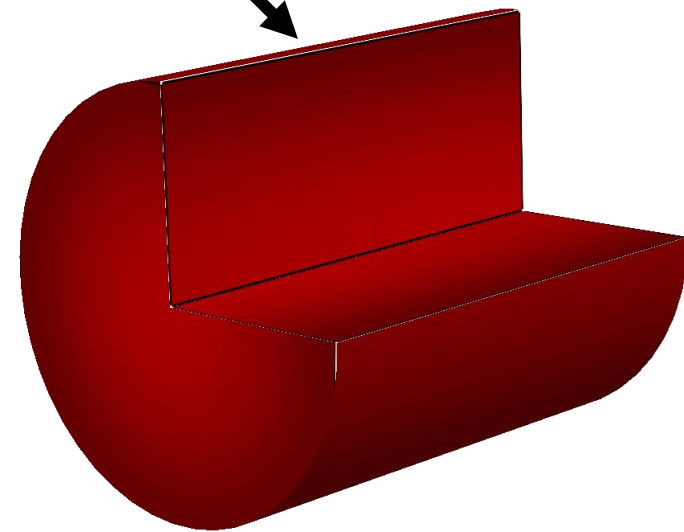
Plasma tomography



Total intensity

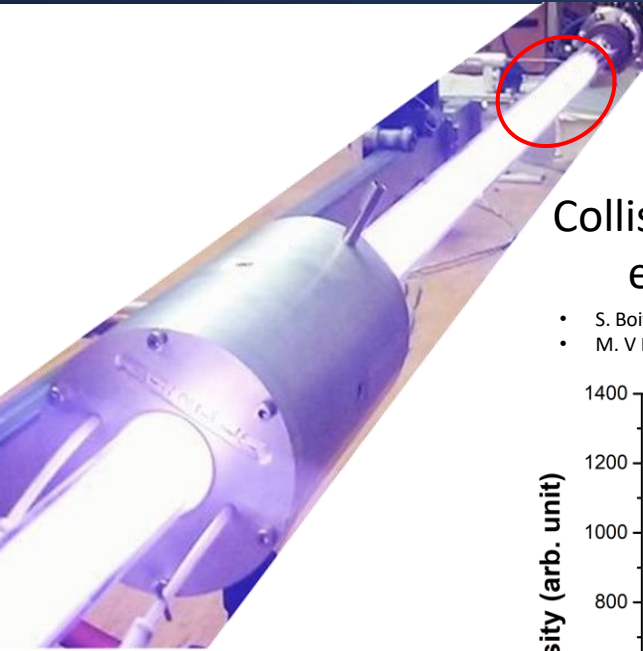


763 nm (Ar)



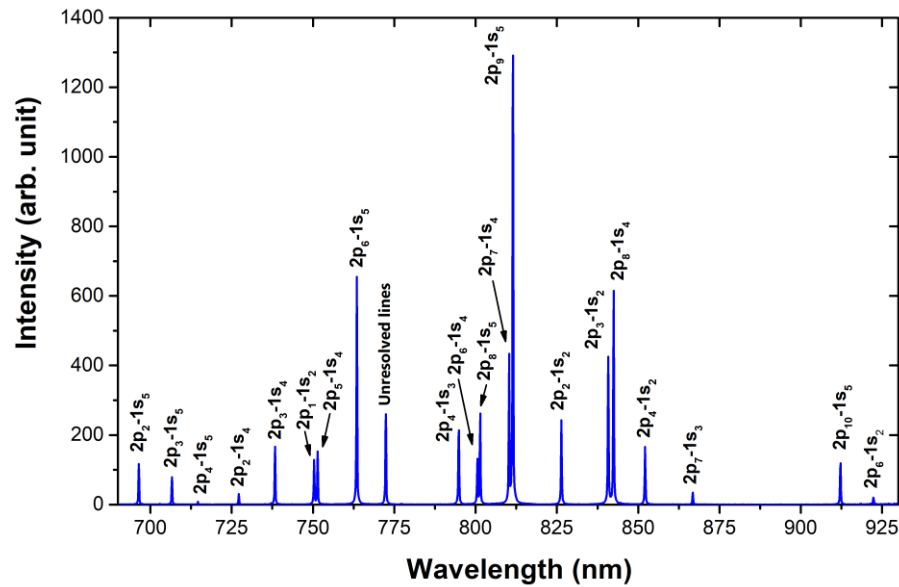
777 nm (O)

Electron temperature mapping



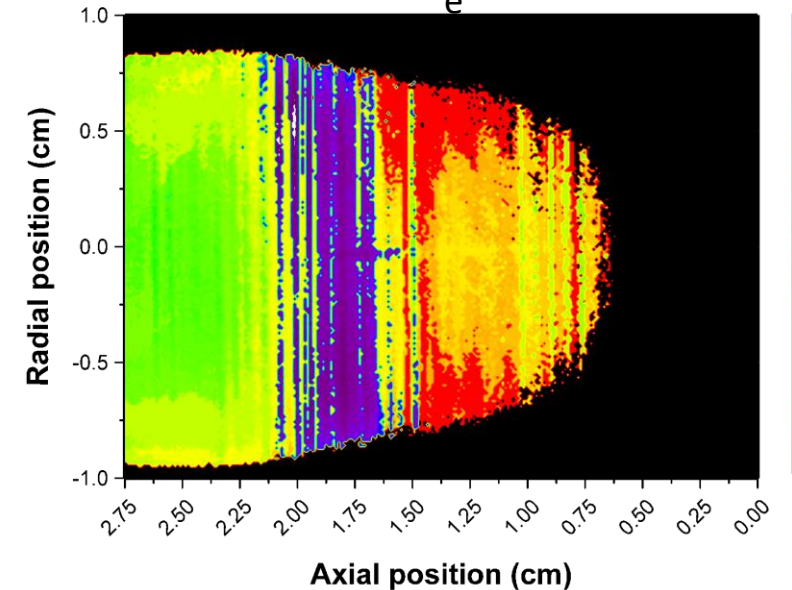
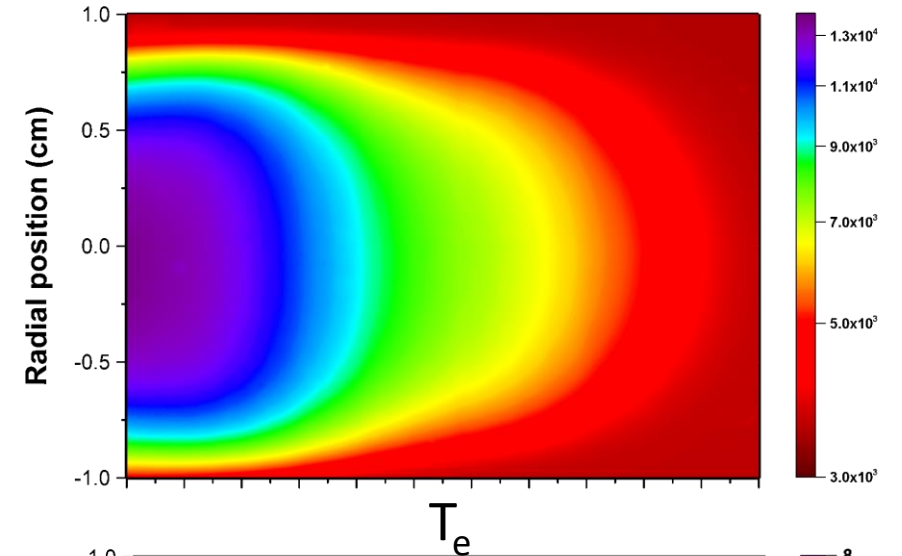
Collisional-radiative model paired with optical emission spectroscopy measurements

- S. Boivin, X. Glad, J. P. Bœuf, and L. Stafford, *Plasma Sources Sci. Technol.* **27**, 095011 (2018)
- M. V Malyshev and V. M. Donnelly, *Phys. Rev. E* **60**, 6016 (1999)



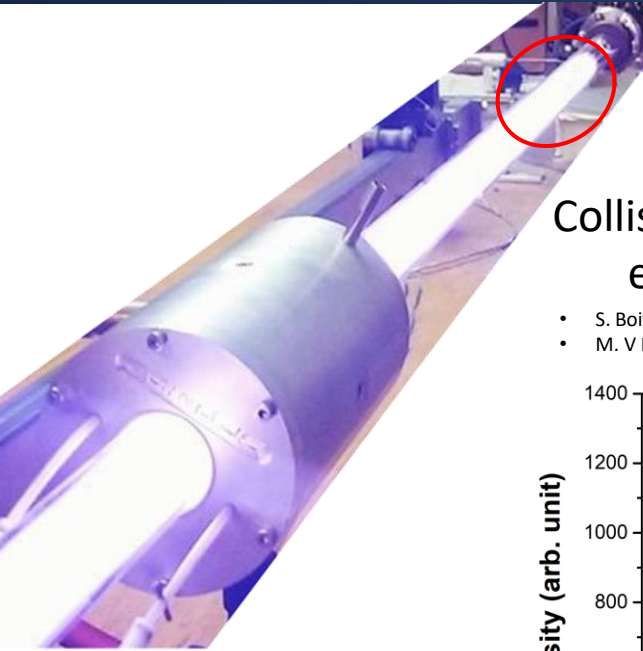
$$I_{\lambda} = A_{ij}n_{2p_i} = A_{ij} \frac{n_e \left(k_1(T_e) n_g + \sum_j k_j(T_e) n_{1s_j} \right) + \sum_{k \neq i} k_k n_g n_{2p_k}}{\sum_j A_{ij} \theta_{ij} + k_2 n_g + \sum_{k \neq i} k_k n_g}$$

Total light intensity



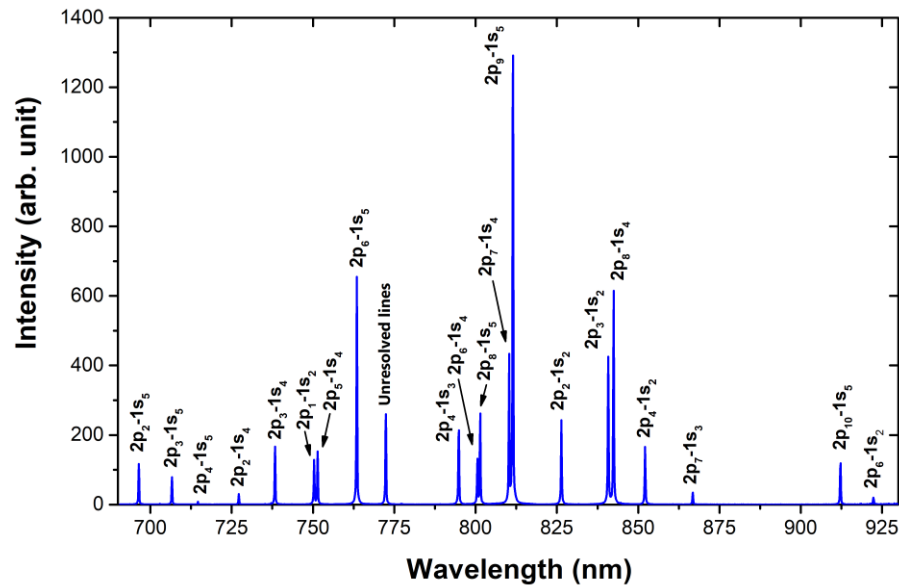
Complete mapping of T_e along the column end

Electron temperature mapping



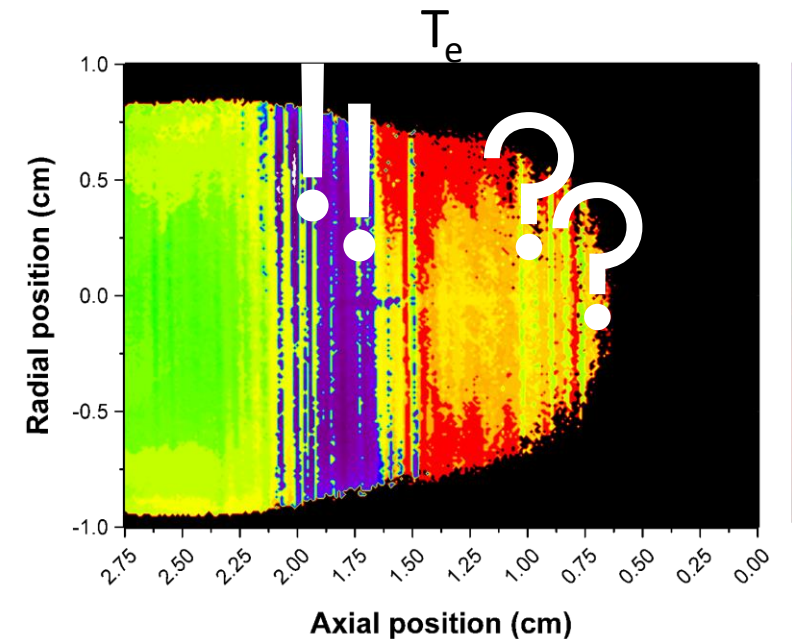
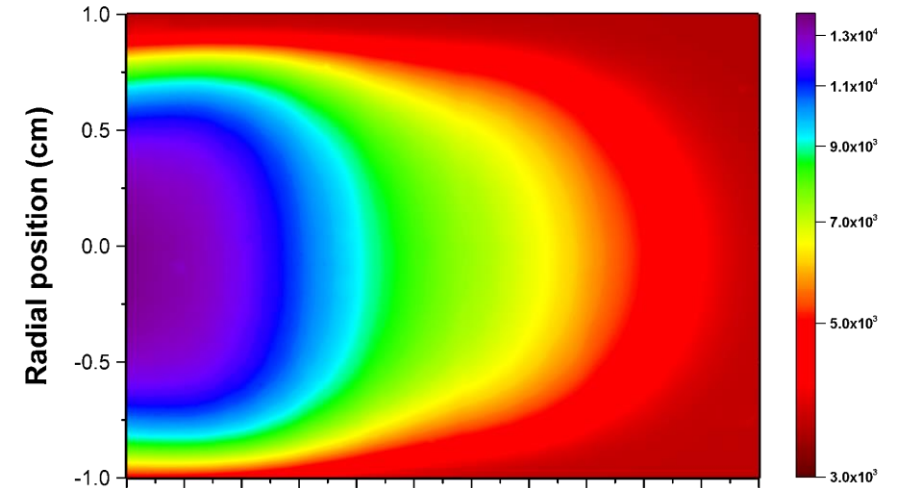
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$$I_{\lambda} = A_{ij} n_{2p_i} = A_{ij} \frac{n_e \left(k_1(T_e) n_g + \sum_j k_j(T_e) n_{1s_j} \right) + \sum_{k \neq i} k_k n_g n_{2p_k}}{\sum_j A_{ij} \theta_{ij} + k_2 n_g + \sum_{k \neq i} k_k n_g}$$

Total light intensity

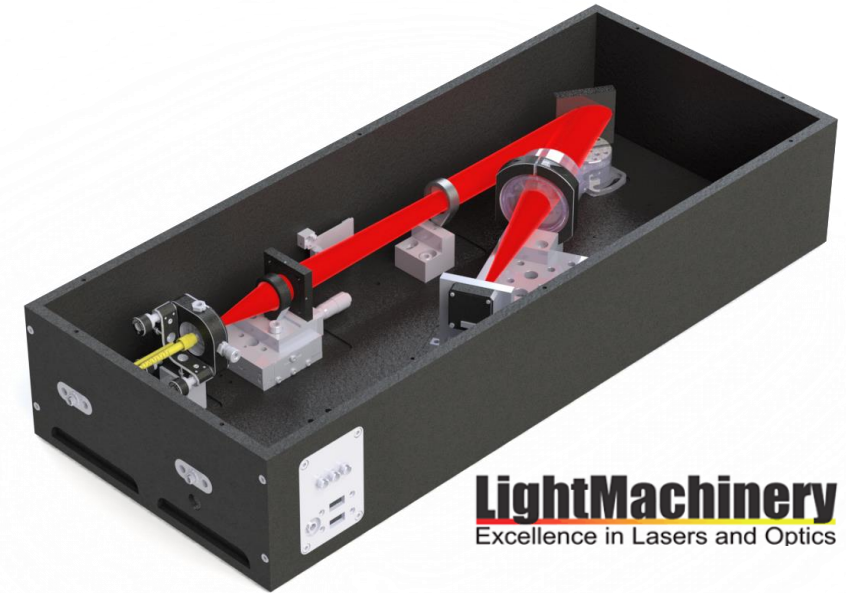
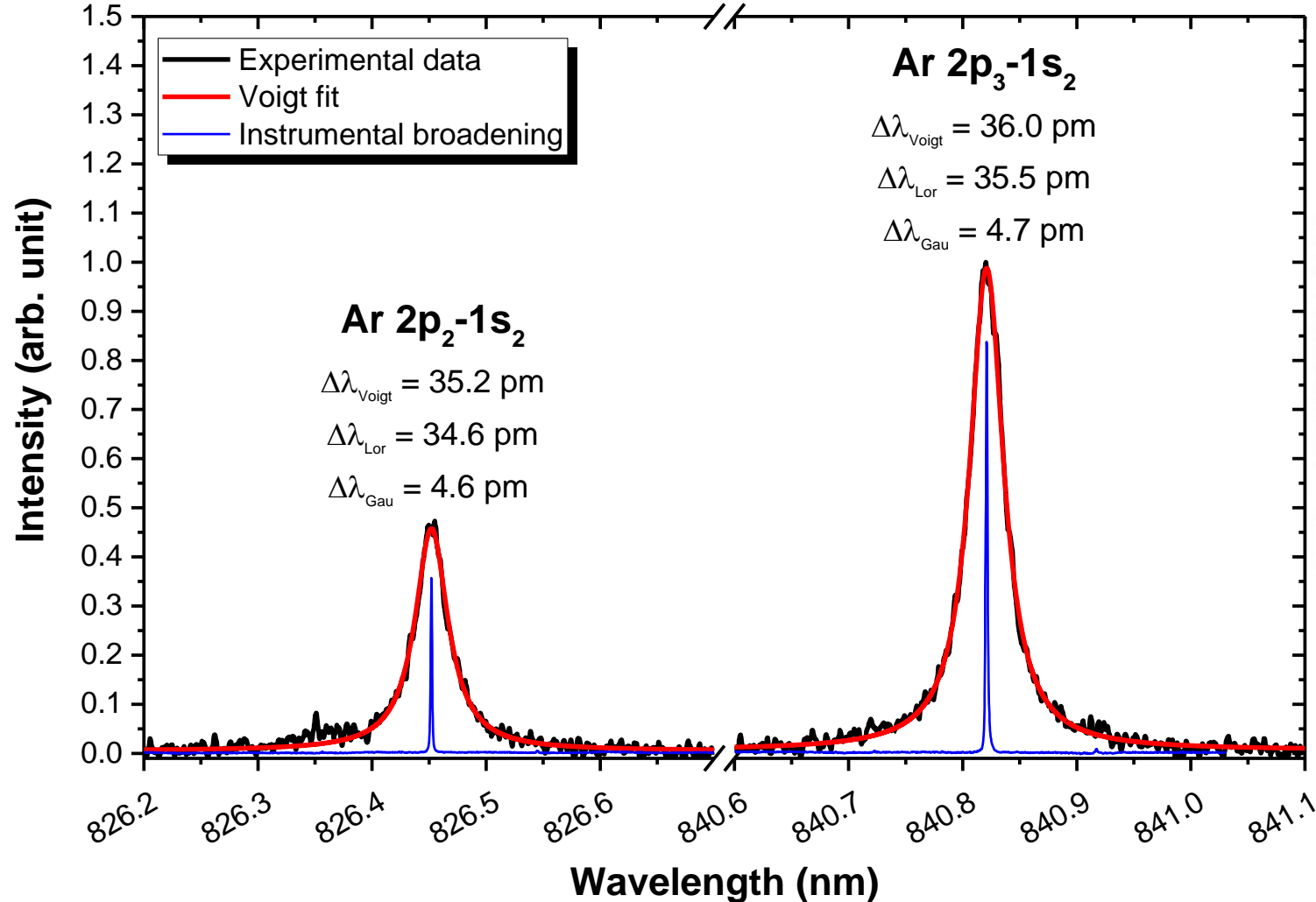


Complete mapping of T_e along the column end

Ultra-high-resolution spectroscopy

Ultra-high-resolution spectroscopy

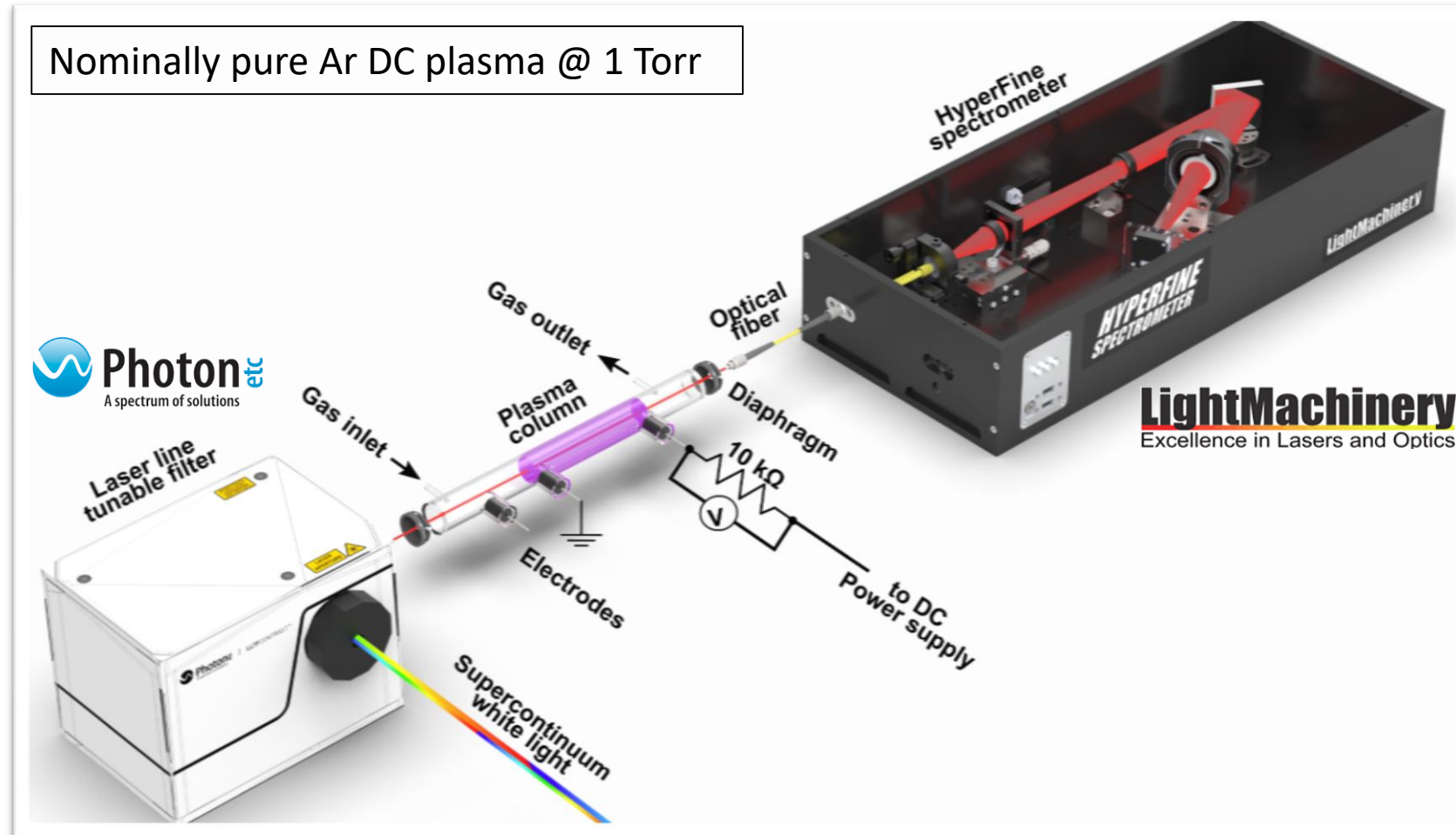
Already popular in: Brillouin spectroscopy, thin-film characterization, photovoltaic characterization



Precise determination of T_g via OES broadening measurements

Ultra-high-resolution spectroscopy

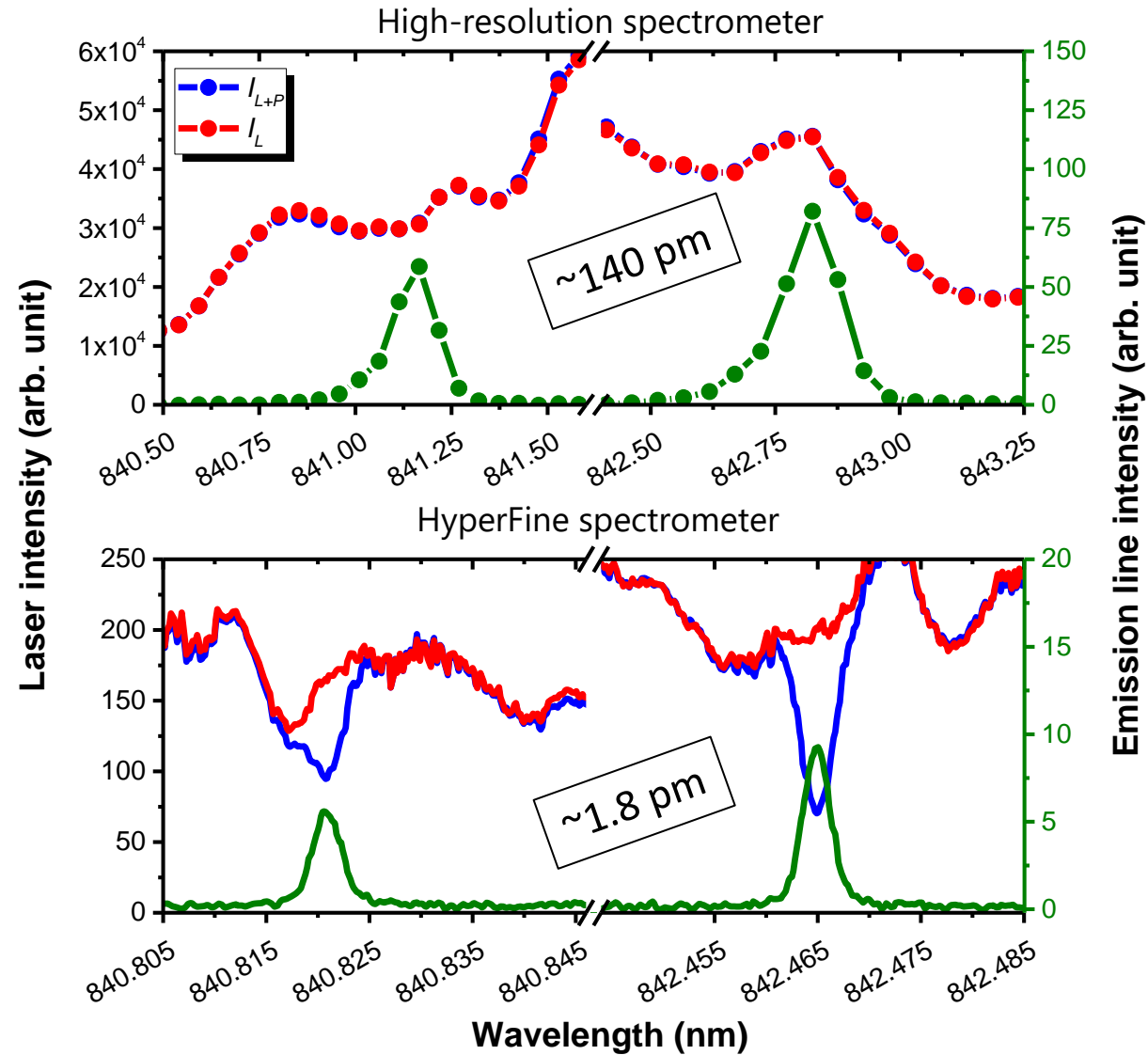
“White light” absorption spectroscopy: obtaining Ar 1s number densities



Supercontinuum laser + laser line tunable filter + ultra-high-resolution spectrometer

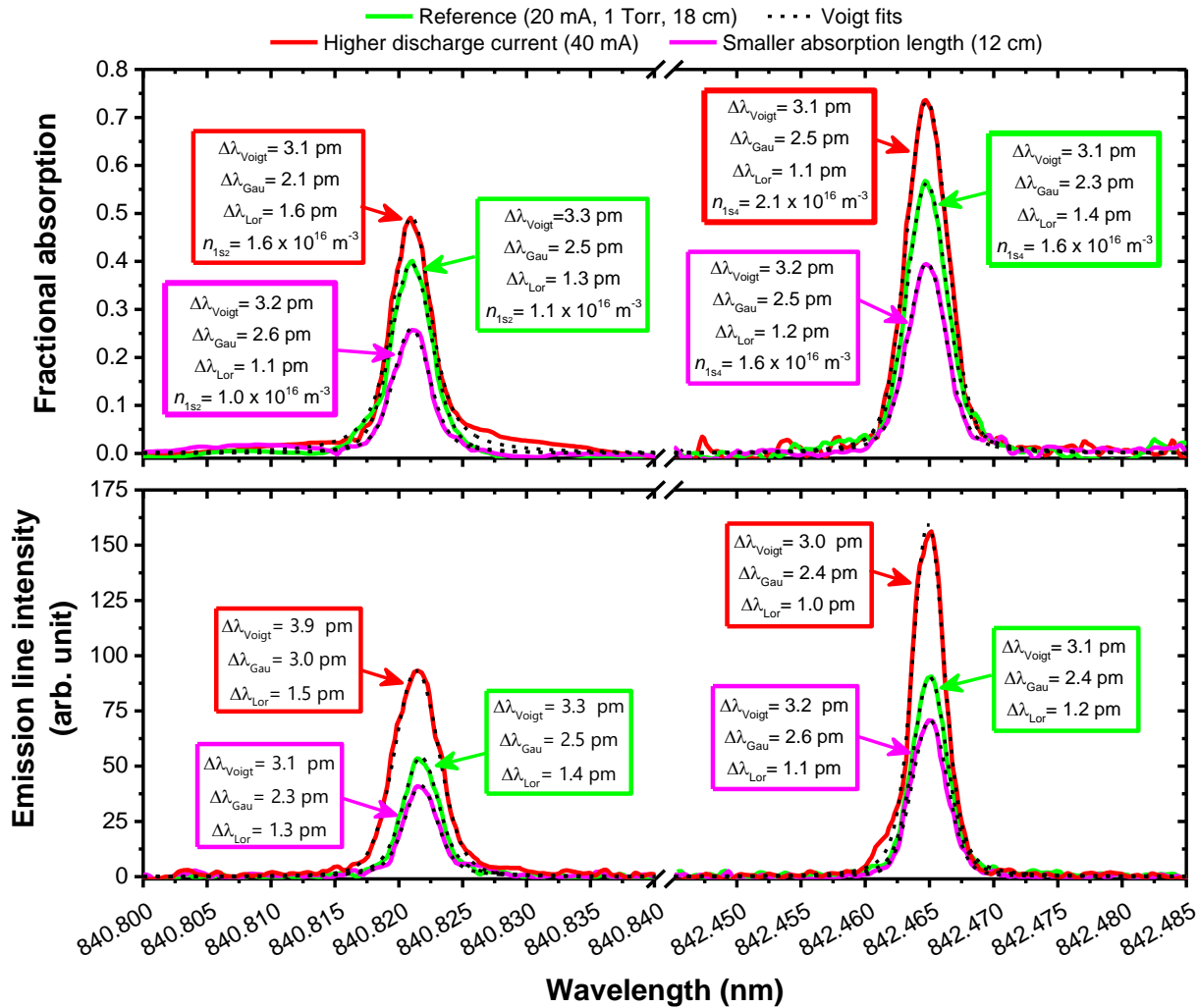
- 400 - 2400 nm
More potential than spectral lamps
- ~ 2.5 nm bandpass
Less invasive than white lights

Ultra-high-resolution spectroscopy



Right spectrometer needed to have reliable measurements!

Ultra-high-resolution spectroscopy



Validation tests:

- Absorption profiles match the emission ones ✓
- Gas temperature of 340 ± 40 K ✓
- Ar $1s_2$ and $1s_4$ number density: 10^{16} m $^{-3}$ range ✓
- $n_{1s_2} < n_{1s_4}$ ✓
- Number densities increase with discharge current ✓
- Fractional absorption decreases with absorption length but number densities are the same ✓

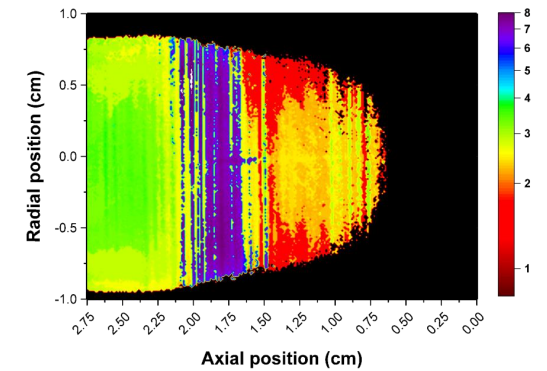
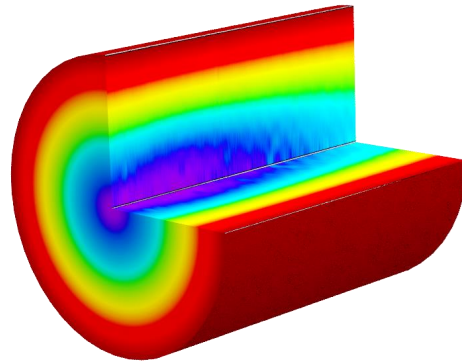
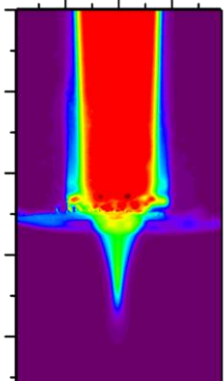
C. M. Ferreira, J. Loureiro, and A. Ricard, J. Appl. Phys. **57**, 82 (1985)

C. M. Ferreira and A. Ricard, J. Appl. Phys. **54**, 2261 (1983)

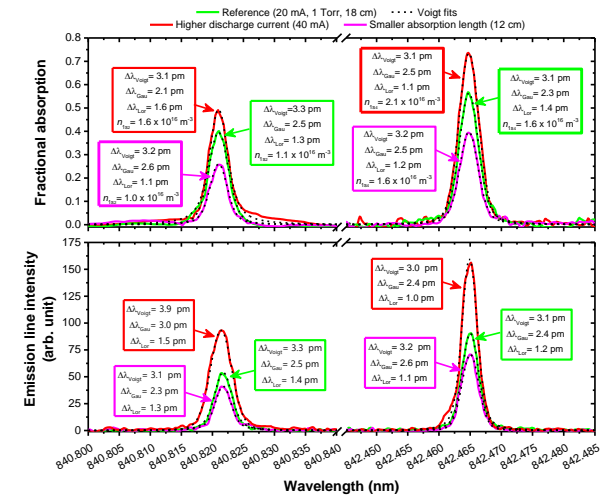
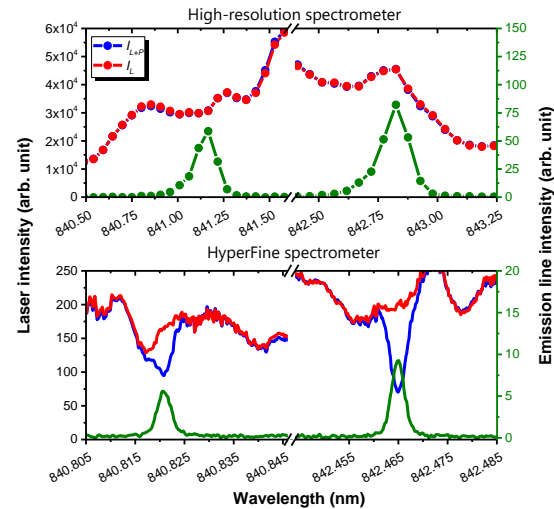
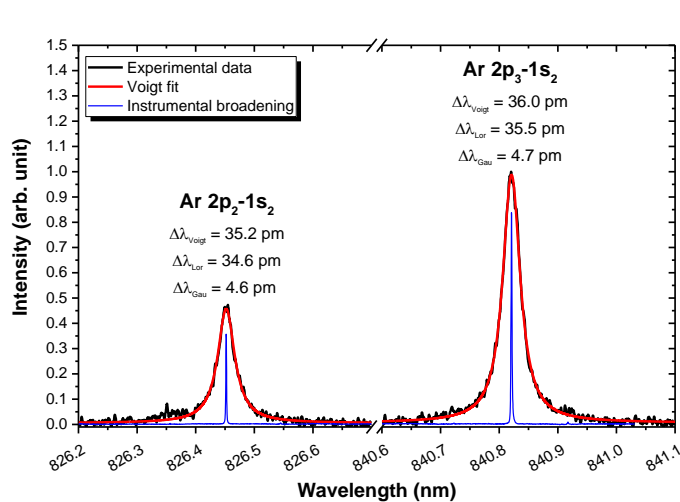
J. Vlček and V. Pelikan, J. Phys. D. Appl. Phys. **22**, 632 (1989)

Conclusion

- Hyperspectral imaging offers huge potential, way beyond simple imaging and point-by-point spectroscopy



- Ultra-high-resolution allows access to plasma parameters with unprecedented precision



- Currently helping in the developpement of instruments designed specifically for plasma sciences

Acknowledgments

Industrial partners



Funding organizations



Thank you for your attention!